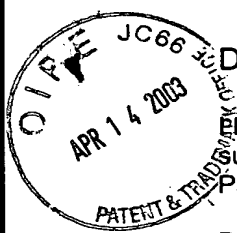


2823



Docket No.: P2001,0011

Whereby certify that this correspondence is being deposited with the United States Postal Service with sufficient postage as first class mail in an envelope addressed to the Assistant Commissioner for Patents, Washington, D.C. 20231, on the date indicated below:

By: Markus Nollf

Date: April 8, 2003

#6/EIE
4/17/3
Smile

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Inventor : Alfred Kersch
Applic. No. : 10/047,814
Filed : January 15, 2002
Title : Reaction Chamber for Processing a Substrate Wafer, and Method for Operating the Chamber
Examiner : William D. Coleman - Art Unit: 2823

RESPONSE

Hon. Commissioner of Patents and Trademarks,
Washington, D. C. 20231

Sir:

Responsive to the Office Action dated March 25, 2003, the following remarks are made:

In deference to the restriction requirement on pages 2 and 3 of the above-identified Office Action, applicants elect group I, claims 1-8, for prosecution at this time.

Applicants reserve the right to file a divisional application including the device claims of group II at a later date.

In view of the foregoing, the early issuance of an Action on the merits of claims 1-8 is solicited.

Respectfully submitted,

Markus Nollf
For Applicant

Markus Nollf
Reg. No. 37,006

Date: April 8, 2003

Lerner and Greenberg, P.A.
Post Office Box 2480
Hollywood, FL 33022-2480
Tel: (954) 925-1100
Fax: (954) 925-1101
/bmb

RECEIVED
APR 16 2003
TECHNOLOGY CENTER 2800